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## BIB DATA SHEET

CONFIRMATION NO. 7189

<b>SERIAL NUMBER</b> 10/519,837	<b>FILING or 371(c) DATE</b> 07/05/2005 <b>RULE</b>	<b>CLASS</b> 438	<b>GROUP ART UNIT</b> 2822	<b>ATTORNEY DOCKET NO.</b> 264197US0PCT
<b>APPLICANTS</b> Shinsuke Sadamitsu, Tokyo, JAPAN; Nobumitsu Takase, Tokyo, JAPAN; Hiroyuki Takao, Tokyo, JAPAN; Koji Sueoka, Tokyo, JAPAN; Masataka Horai, Tokyo, JAPAN; <i>mw</i>				
<b>** CONTINUING DATA *****</b> This application is a 371 of PCT/JP03/08333 06/30/2003				
<b>** FOREIGN APPLICATIONS *****</b> JAPAN 2002-208515 07/17/2002 <i>mw</i>				
<b>** IF REQUIRED, FOREIGN FILING LICENSE GRANTED **</b>				
Foreign Priority claimed 35 USC 119(a-d) conditions met Verified and Acknowledged	<input checked="" type="checkbox"/> Yes <input type="checkbox"/> No <input checked="" type="checkbox"/> Yes <input type="checkbox"/> No Examiner's Signature <i>[Signature]</i>	<input type="checkbox"/> Met after Allowance Initials	<b>STATE OR COUNTRY</b> JAPAN	<b>SHEETS DRAWINGS</b> 8
			<b>TOTAL CLAIMS</b> 17	<b>INDEPENDENT CLAIMS</b> 4
<b>ADDRESS</b> OBLON, SPIVAK, MCCLELLAND, MAIER & NEUSTADT, P.C. 1940 DUKE STREET ALEXANDRIA, VA 22314 UNITED STATES				
<b>TITLE</b> High-resistance silicon wafer and process for producing the same				
<b>FILING FEE RECEIVED</b> 1230	FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following:		<input type="checkbox"/> All Fees <input type="checkbox"/> 1.16 Fees (Filing) <input type="checkbox"/> 1.17 Fees (Processing Ext. of time) <input type="checkbox"/> 1.18 Fees (Issue) <input type="checkbox"/> Other _____ <input type="checkbox"/> Credit	